

Docket No.: SON-2413/DIV  
(PATENT)

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

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In re Patent Application of:  
Shigeru Moriya, et al.

Application No.: Not Yet Assigned

Art Unit: 2814

Filed: Concurrently Herewith

Examiner: T. Le

For: MASK, METHOD OF PRODUCING MASK,  
AND METHOD OF PRODUCING  
SEMICONDUCTOR DEVICE

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**FIRST PRELIMINARY AMENDMENT**

MS Patent Application  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

**INTRODUCTORY COMMENTS**

Prior to examination on the merits, please amend the above-identified U.S. patent application as follows:

**Amendments to the Specification** begin on page 2 of this paper.

**Amendments to the Claims** are reflected in the listing of claims which begins on page 3 of this paper.

**Remarks/Arguments** begin on page 7 of this paper.